

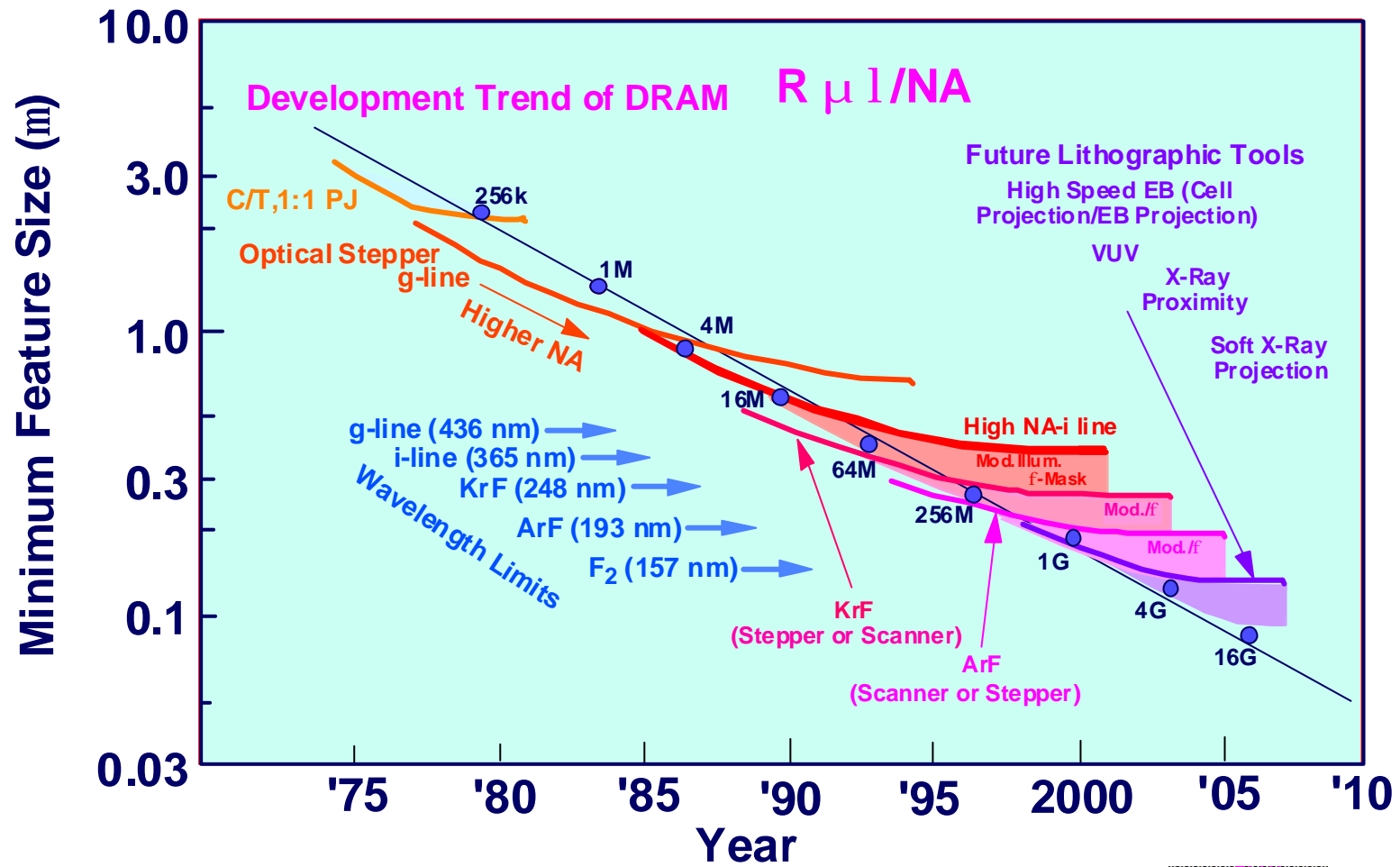


Theoretical Estimation on the Balance Between the Absorption Coefficient and Etching Resistance of Various Polymers at 13 nm

Nobuyuki Matsuzawa, Hiroaki Oizumi, Shigeyasu Mori,
Shigeo Irie, Ei Yano, Shinji Okazaki and Akihiko Ishitani

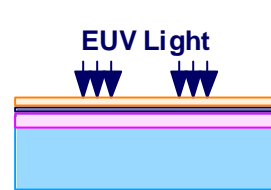
EUV Lithography Laboratory,
Atsugi Research Center,
Association of Super-Advanced Electronics Technologies
(ASET)





■ Introduction 2. Resist Processes for EUV Lithography

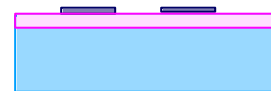
Thin Resist Process



Exposure



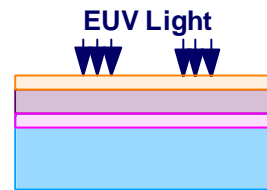
Development



Hard Mask Etching



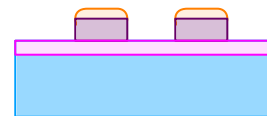
Bi-Layer Process



Exposure



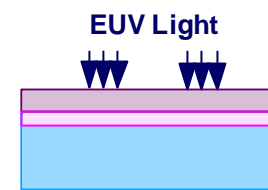
Development



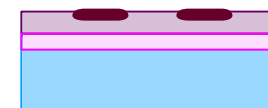
Under Layer Dry Etching



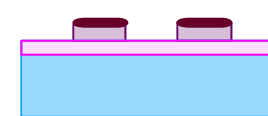
Silylation Process



Exposure



Silylation



Substrate Dry Etching & Resist/Hard Mask Removal



Absorption of polymers at 13nm is an important factor for molecular design



■ Introduction 3. Previous Study (G. D. Kubaik et al. JVST B 1992, 10, 2593)

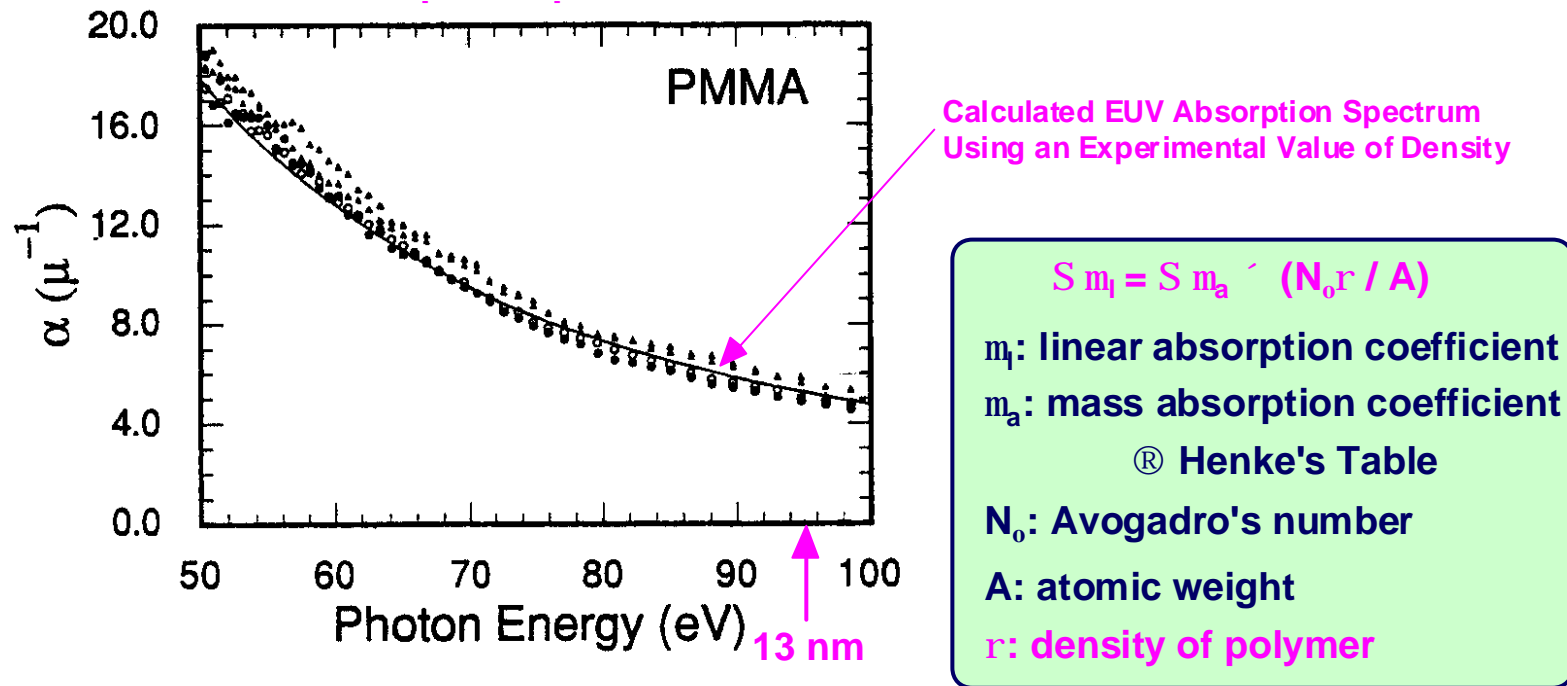


FIG. 3. Plot of the linear absorption coefficient vs photon energy of PMMA films determined from transmittance measurements made for four film thicknesses (Δ : 75 nm; \blacktriangle : 150 nm; \circ : 163 nm; and \bullet : 220 nm). Solid curve is calculated from mass absorption coefficients and measured film density.



■ Introduction 4. Relative Atomic Absorption from Henke's Table

H:	1
C:	23.8
N:	49.6
O:	93.4
F:	141
Si:	13.6



$H < Si < C < N < O < F$



■ The Aim of This Work

- We would like to predict the absorption quicker than doing measurements

- Often, there are no experimental density available for resist polymers



Prediction of density of polymers



Prediction of the absorption



Molecular Design of Resist Polymers



■ Calculation 1. Comparison to the Experiment

- Mass Absorption Coefficient by **Henke et al.**

B. L. Henke, E. M. Gullikson and J. C. Davis, *Atomic Data and Nuclear Data Tables*, 54 (1993) 181.

- Polymer Density Calculated by Using the **Graph-Theoretical Treatment**
Derived by **Bicerano et al.** Implemented in the Program system "**POLYMER**".

J. Bicerano, *Predictions of the Properties of Polymers from their Structures*, Marcel Dekker: New York, 1993.

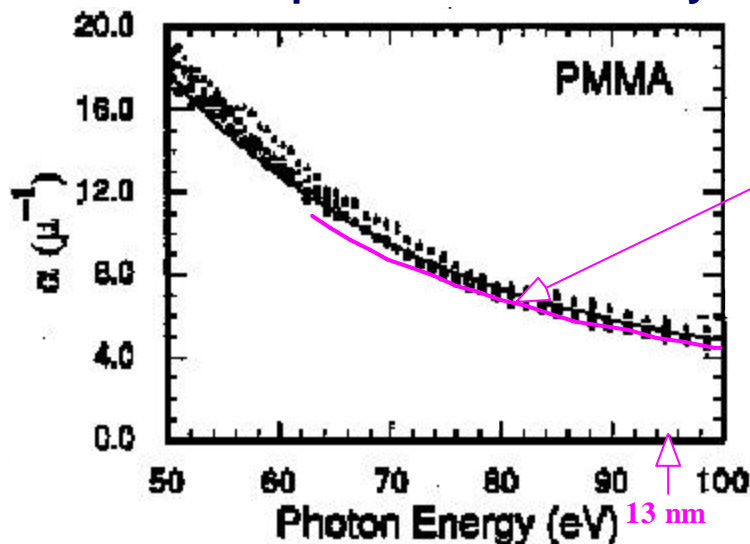
L. B. Kier and L. H. Hall, *Molecular Connectivity in Chemistry and Drug Research*, Academic Press: New York 1976.

L. B. Kier and L. H. Hall, *Molecular Connectivity in Structure-Activity Analysis*, John-Wiley & Sons: New York (1986).

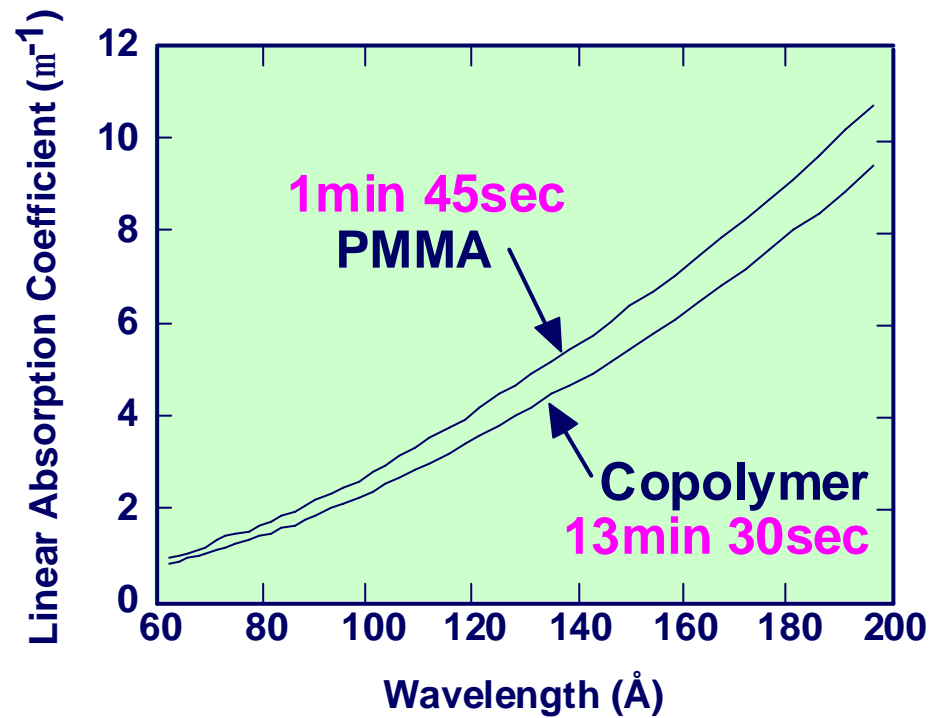
The "POLYMER" program is available from **MSI Inc.**, San Diego, CA.

Accuracy of density prediction: Average error: **2.2 %**

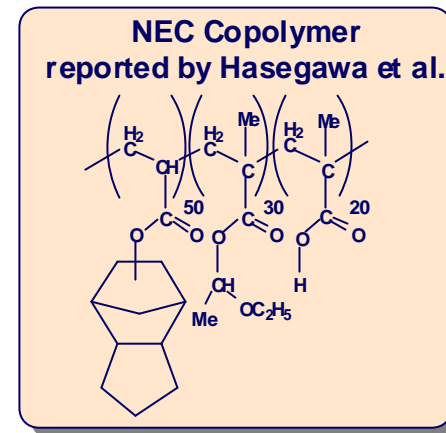
- Comparison to the Experimental Result by G. D. Kubaik et al.



■ Calculation 2. Computational Time Required

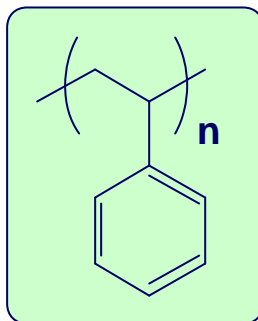


Note: The time shown includes time to make the input deck for computation

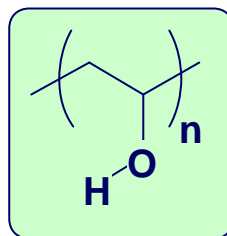


Ref: Nakano et al. Proc. SPIE 1994, 2195, 194; ibid 1995, 2438, 322

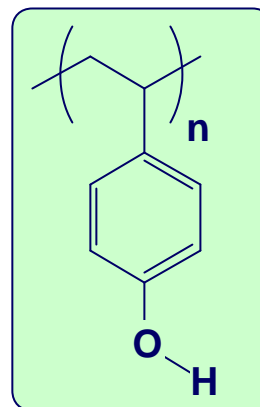
Results 1. Results on Some General Polymers



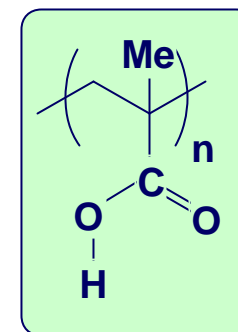
2.79 /m
43.3 %
75.7 %



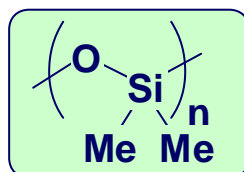
5.27 /m
20.6 %
59.0 %



3.80 /m
32.0 %
68.4 %



5.38 /m
19.9 %
58.4 %



2.68 /m
44.8 %
76.5 %

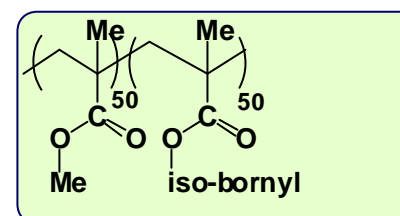
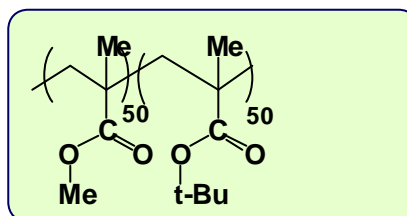
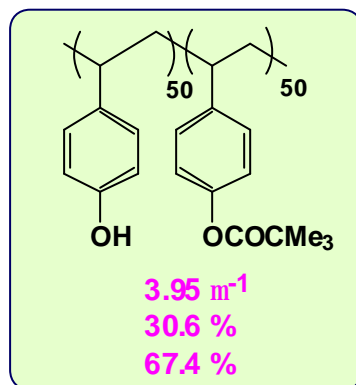
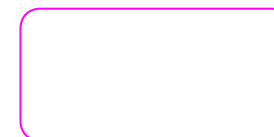
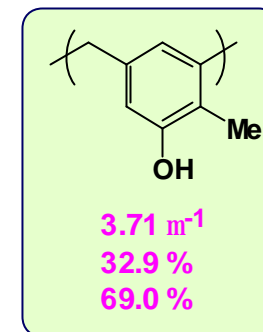
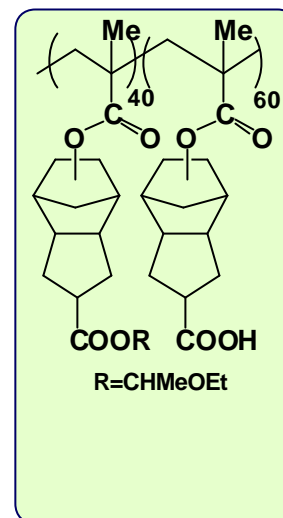
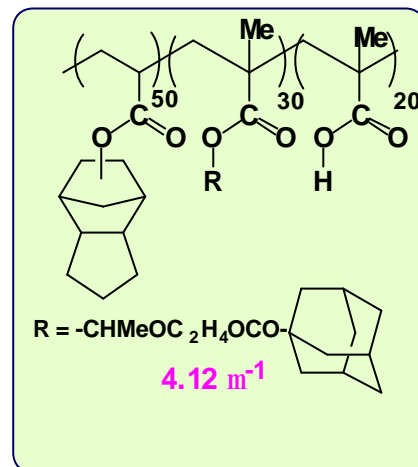
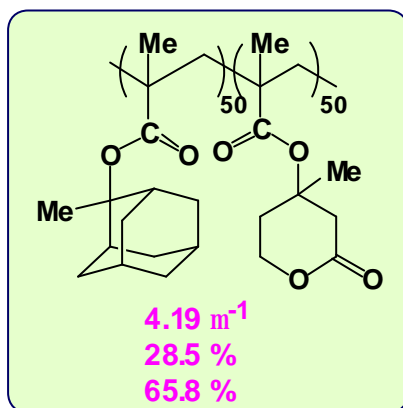


1.25 /m
68.8 %
88.3 %

linear abs coeff.
T @ 3000 Å
T @ 1000 Å



Results 2. Results on Some Reported Resist Polymers



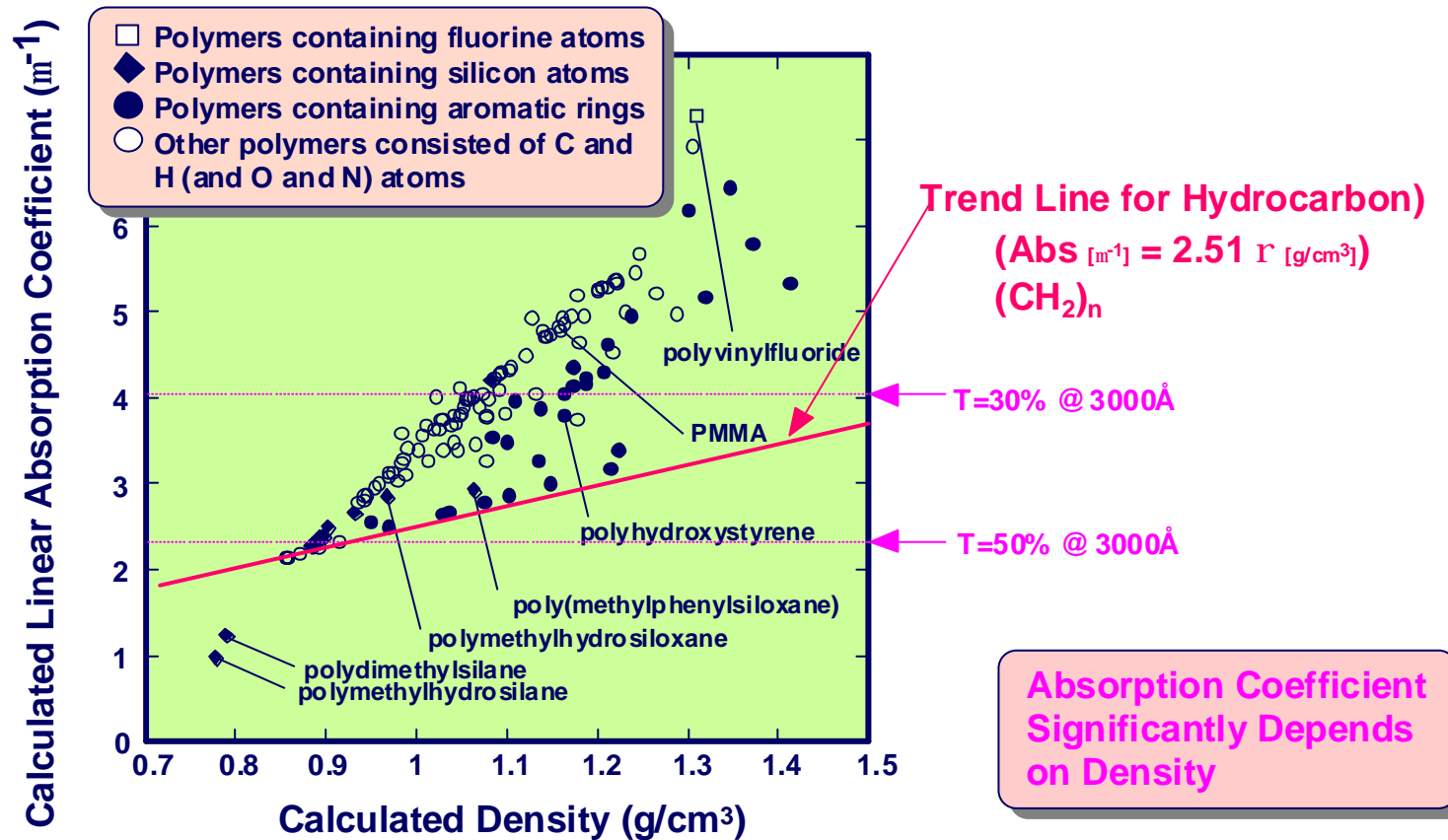
■ Results 3. Calculated Polymers

More than 140 polymers were calculated
acrylates, methacrylates, polyalkanes, polyvinylalcohol, polyvinylphenols,
fluorinated polymers, silanes, siloxanes

polyacenaphthylene, polyacetal, polyacrylamide, polyacrylic acid, polyacrylonitrile, polybenzyl-acrylate, polybenzylmethacrylate, polybutadiene, poly(1-butene), poly(2-butoxyethyl acrylate), poly(n-butyl acrylate), poly(t-butyl acrylate), poly(t-butylaminoethylmethacrylate), poly(n-butyl methacrylate), poly(sec-butyl methacrylate), poly(t-butyl methacrylate), poly(1,4-butylene adipate), poly(1,4-butylene terephthalate), poly(t-butyl styrene), polycaprolactone, poly-carbonate, poly(cyclohexyl acrylate), poly(cyclohexyl methacrylate), poly(n-decyl acrylate), poly(n-decyl methacrylate), poly(di-t-butyl vinylpyridine), poly(2,6-dimethyl-1,4-phenylene oxide), poly(2,2-dimethyl-1,3-propylene succinate), poly(dimethylaminoethyl methacrylate), poly(2,3-dihydrofuran), poly-diethoxysiloxane, polydiethylsiloxane, poly-dimethylsiloxane, polydimethylsilane, poly(4,4'-diisopropoxy-2,2'-diphenylpropane fumarate), poly(2-(2-ethoxyethoxy)-ethyl acrylate), poly(ethyl acrylate), poly(ethyl methacrylate), polyethylene, poly(ethylene adipate), poly(ethylene azelate), poly(ethylene glycol), poly(ethylene succinate), poly(ethylene terephthalate), poly(2-ethylhexyl acrylate), poly(2-ethylhexyl methacrylate), poly(ethyl methacrylate), poly-(hexadecyl methacrylate), poly(hexafluoro-propylene oxide), poly(hexamethylene sebacate), poly(n-hexyl acrylate), poly(n-hexyl methacrylate), poly(p-hydroxy benzoate), poly(hydroxybutyric acid), poly(4-hydroxybutyl-acrylate), poly(2-hydroxybutylacrylate), poly(2-hydroxyethylmethacrylate), poly(2-hydroxy-propylacrylate), poly(2-hydroxypropyl-methacrylate), poly(4-hydroxystyrene), poly-imide, poly(isobomyl-acrylate), poly(isobornyl-methacrylate), poly(isobutyl acrylate), poly-isobutylene, poly(isobutyl methacrylate), poly-isoprene, poly(isopropyl acrylate), poly(isopropyl methacrylate), poly(lauryl acrylate), poly(lauryl methacrylate), polymethacrylamide, poly(methacryl acid), polymethacrylonitrile, poly(2-methoxyethyl acrylate), poly(4-methoxy-styrene), poly(methyl acrylate), poly(methyl methacrylate), poly(methylhexadecylsiloxane), poly(methyl-hexylsiloxane), poly(methylhydro-silane), poly(methylhydrosiloxane), poly(methyloctadecylsiloxane), poly(methyloctyl-siloxane), poly(methylphenylsiloxane), poly(4-methyl-1-pentene), poly(a-methylstyrene), poly(4-methylstyrene), poly(methyltetradecyl-siloxane), poly(neopentylmethacrylate), poly(neopentyl glycol sebacate), poly(octadecyl acrylate), poly(octadecyl methacrylate), poly(octyl acrylate), poly(octyl methacrylate), poly(2-phenoxyethyl acrylate), poly(2-phenoxyethyl methacrylate), poly(2-phenyl methacrylate), poly(phenylethyl methacrylate), poly(propyl methacrylate), poly(propyl acrylate), poly(propylene), poly(propylene glycol), polystyrene, polytetrafluoroethylene, polytetrahydrofuran, poly(tetrahydrofurfuryl methacrylate), poly(tetrahydrofurfuryl acrylate), poly(tridecyl methacrylate), poly(trimethylene adipate), poly(trimethylene glutarate), poly(trimethylene succinate), poly(vinyl acetate), poly(vinyl alcohol), poly(vinyl biphenyl), poly(vinyl carbazole), poly(vinyl cinnamate), poly(vinyl ethylether), poly(vinyl fluoride), poly(vinylidene fluoride), poly(vinyl laurate), poly(vinyl methylether), poly(vinyl methylketone), poly(vinyl naphthalene), poly(vinyl pivalate), poly(vinyl propionate), poly(2-vinyl pyridine), poly(vinyl stearate), Nylon-6, Nylon-6/6, Nylon-6/9, Nylon-6/10, Nylon-6/12, Nylon-11, Nylon-12



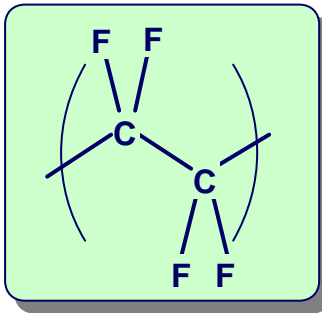
Results 4. Calculated Linear Absorption Coefficient at 13 nm for Various Polymers



■ Results 5.

Results on Fluorinated Polymers

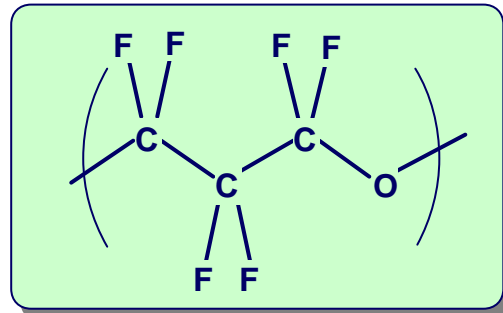
Density
Linear Absorption
T @ 1000 Å



2.053 g/cm³

16.4 /m

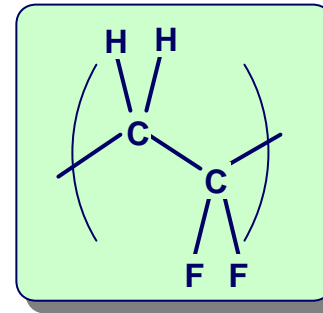
0.7 %



2.022 g/cm³

16.1 /m

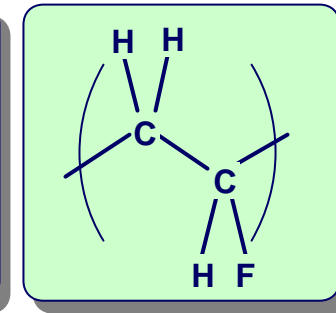
0.8 %



1.606 g/cm³

11.0 /m

3.7 %



1.310 g/cm³

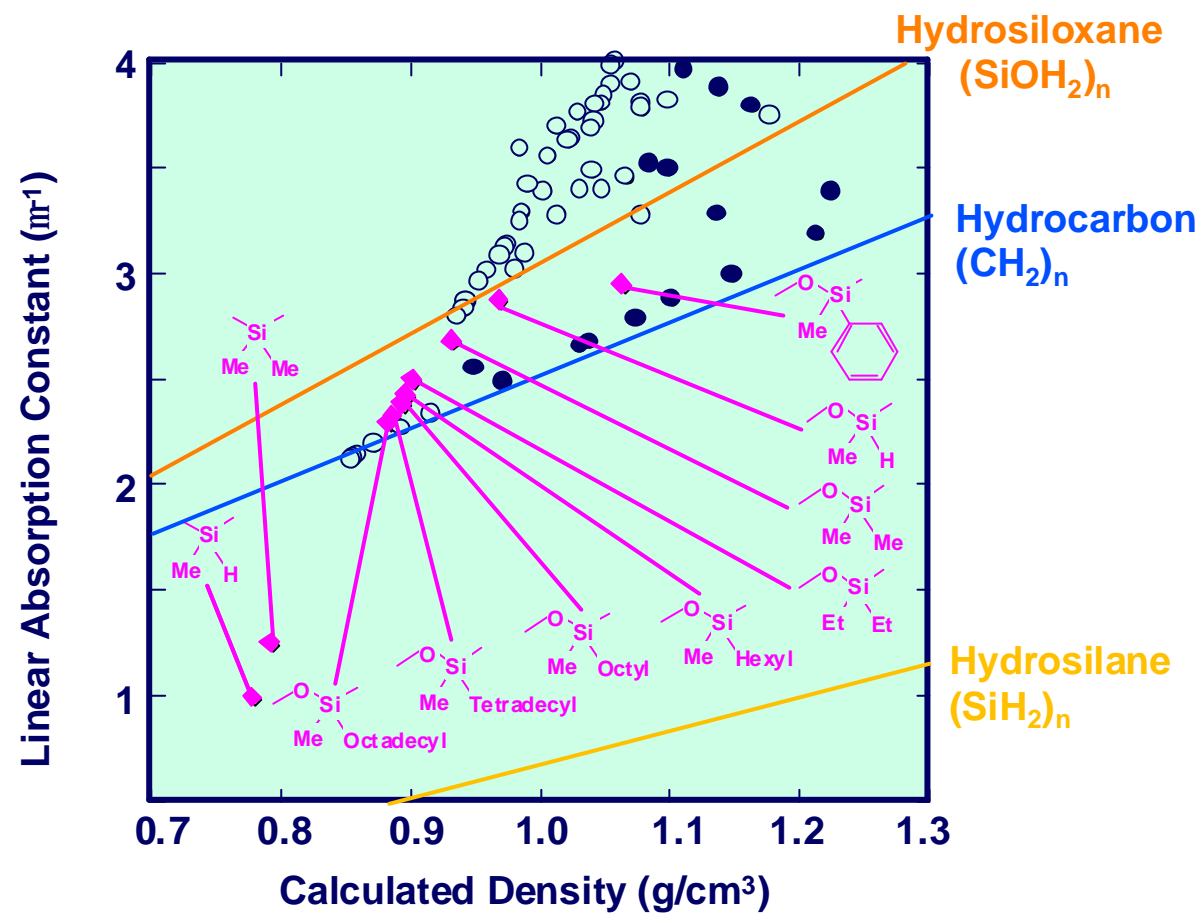
7.3 /m

11.2 %

Values for fluorinated
polymers are too large

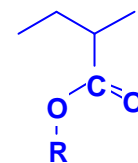
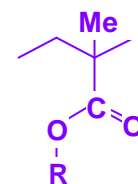
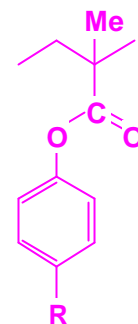
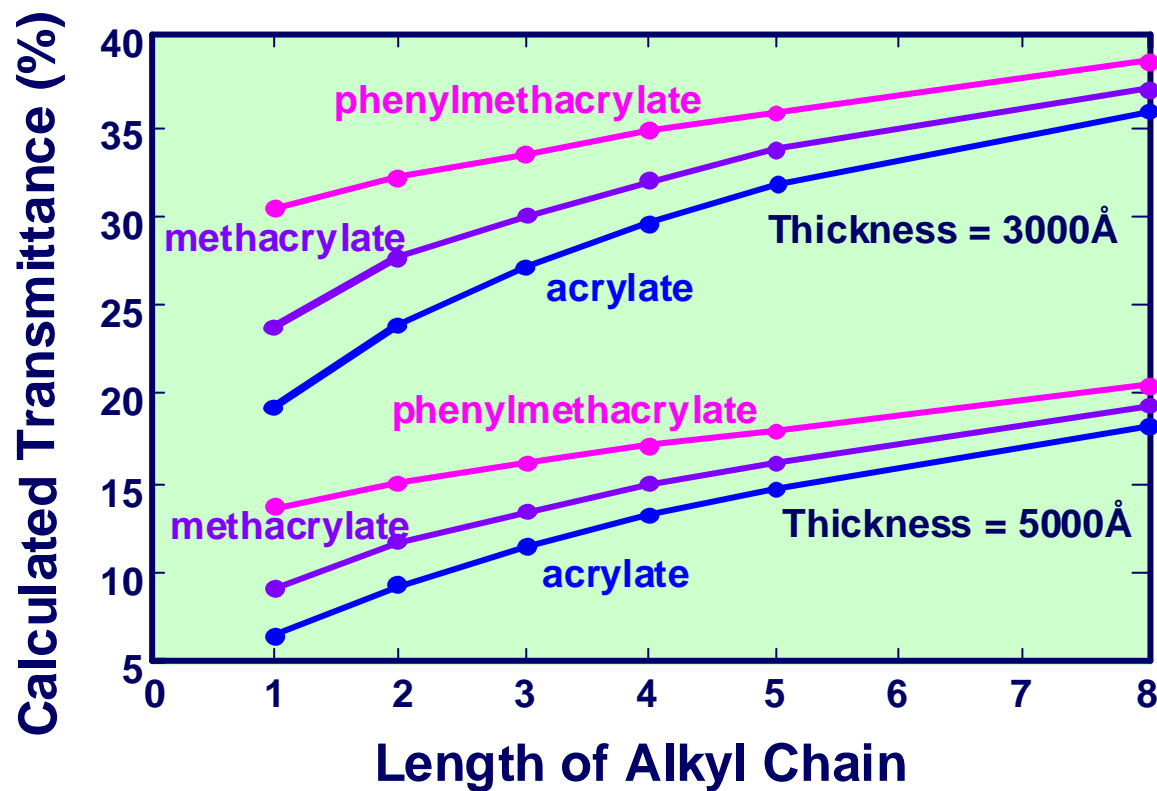


Results 6. Silicon Containing Polymers

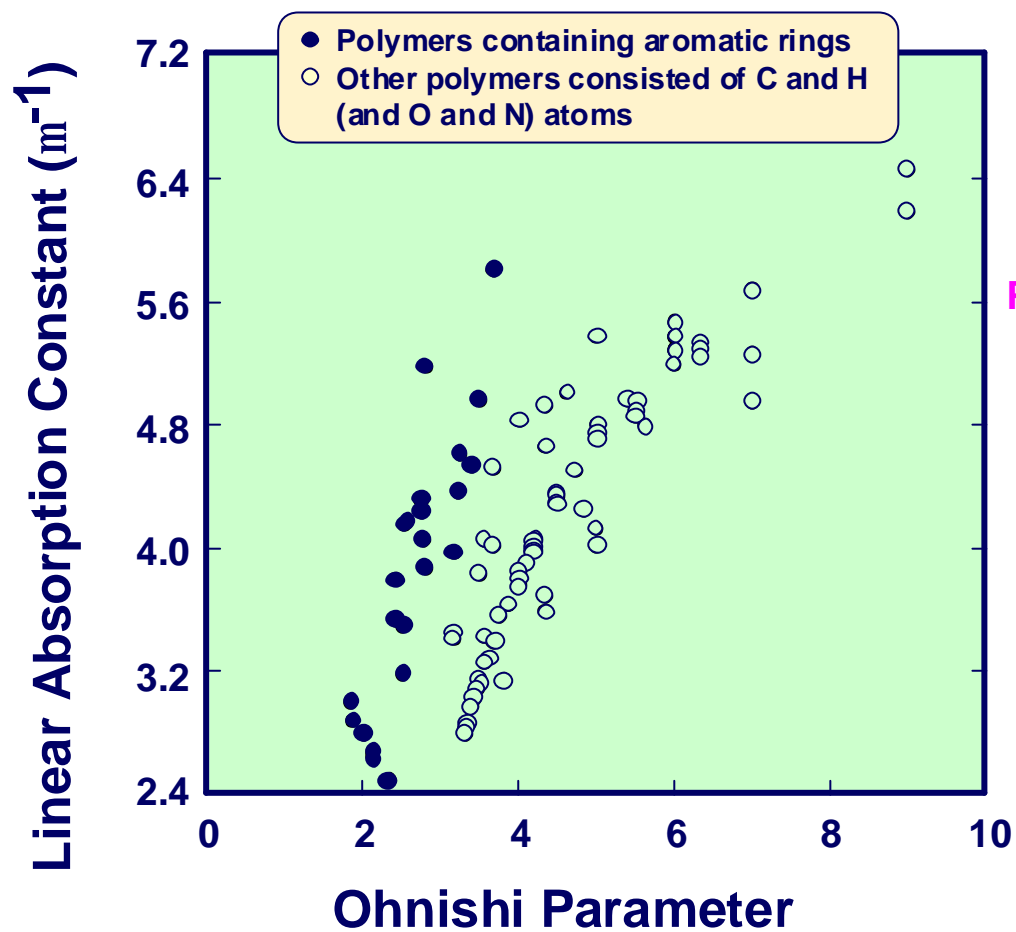


Results 7.

Effect of the Addition of a Phenyl Ring or the Elongation of Alkyl Chain



Results 8.



Phenyl Substitution leads to
Lower Absorption and
Higer Etching Resistance

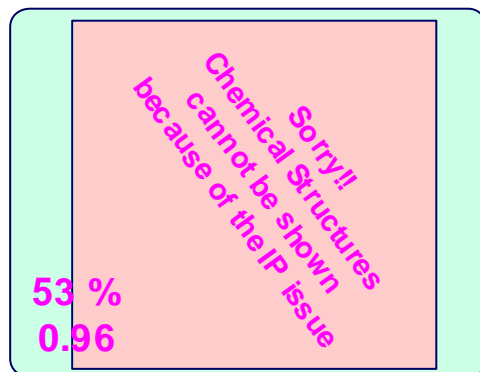
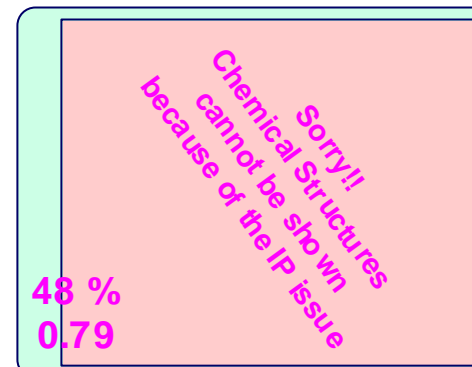
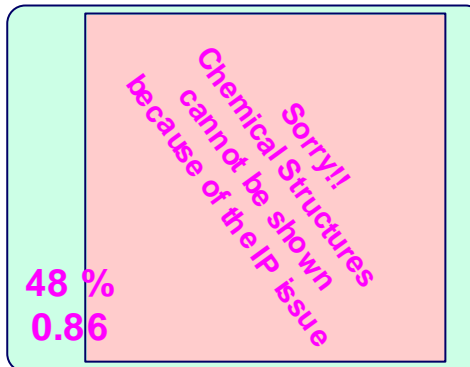
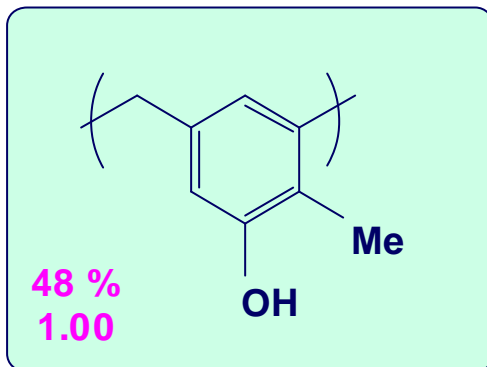


Single Layer Resist Process?



■ Results 9.

T (@200nm)
Normalized Ohnishi Param.



Further designing of novel
polymers for EUVL are
now in progress!!